Abstract

The invention relates to a device for determination of alignment errors of structures (6) which are present on a substrate (5) or which have been applied to it with the following features:

- a substrate holder (2) for accommodating the substrate (5) with the structures (6) and
- detection means for detecting X-Y positions of first markings (7) on the substrate (5) and/or second markings (11, 11') on the structures (6) by moving the substrate (5) or the detection means in a first coordinate system,

characterized in that

in a second coordinate system which is independent of the first coordinate system X'-Y' structure positions for the structures (6) are given whose respective distance from the X-Y positions of the first markings (7) and/or second markings (11, 11') can be determined by the device.

Furthermore the invention relates to a corresponding method.

Figure 5 in this respect